

WHAT IS CLAIMED IS:

1. Power supply for receiving a power value setting signal setting strength of power from said power supply and a power on/off instruction to set on or off of the power to produce the power supply power, wherein

in response to detection of a state in which a power sense signal according to a value obtained by sensing the strength of the power exceeds a predetermined value when said power on/off instruction is off, the power supply power is suppressed regardless of a state in which the power on/off instruction is set to on.

2. Power supply according to claim 1, wherein:  
the power is under closed-loop control using the power sense signal; and

when the power sense signal exceeds a predetermined threshold value, either one of the signals used for the closed-loop control is set to a zero level to thereby suppress the power.

3. Power supply according to claim 1, comprising abnormality sensing means for assuming an abnormality if the power sense signal exceeds a predetermined threshold value when the power on/off instruction is off to provide an abnormality sense signal.

4. Power supply according to claim 1, comprising means for displaying an abnormality indication in response to occurrence of an event in which the power

10082160, 022502

sense signal exceeds a predetermined threshold value when the power on/off instruction is off, to provide an abnormality sense signal.

5. A semiconductor making apparatus, comprising:  
a processing chamber for processing a semiconductor wafer;

a power supply for providing a current, a voltage, or power as an output item necessary for the semiconductor wafer processing;

a control microcomputer for setting a strength of the output item to said power supply and setting the outputting of the output item; and

output sensing means for sensing the output item to provide an output sense signal according to a value obtained by sensing the output item, wherein  
if the output sense signal exceeds a predetermined threshold value when the outputting of the output item is off, the processing for a subsequent semiconductor wafer to be processed is stopped.

6. A semiconductor making apparatus, comprising:  
a processing chamber for processing a semiconductor wafer;

a power supply for supplying a current, a voltage, or power as an output item necessary for the semiconductor wafer processing;

a control microcomputer for setting strength of the output item to said power supply and setting the outputting of the output item to on or off; '

sensing means for sensing the output item and outputting an output sense signal according to a value obtained by sensing the output item; and

abnormality display means for displaying an abnormality indication in response to an event in which the output sense signal exceeds a predetermined threshold value when the outputting of the output item is off, the processing is stopped for a subsequent semiconductor wafer to be processed.

7. A semiconductor wafer fabricating method, comprising the steps of:

setting, to a power supply for supplying an output of a current, a voltage, or power as an output item necessary for processing of a semiconductor wafer, strength of the output item;

setting outputting of the output item to on or off;

sensing the output item and for providing an output sense signal according to a value obtained by sensing the output item; and

stopping the processing for a subsequent semiconductor wafer to be processed in response to an event in which the output sense signal exceeds a predetermined threshold value when the outputting of the output item is off in said step of setting the outputting of the output item to on or off.

8. A semiconductor wafer fabricating method, comprising the steps of:

setting, to a power supply for supplying a current, a voltage, or power as an output item necessary for processing of a semiconductor wafer, a strength of the output item;

setting outputting of the output item to on or off;

sensing the output item to provide an output sense signal according to a value obtained by sensing the output item; and

assuming occurrence of an abnormality and displaying an abnormality indication in response to an event in which the output sense signal exceeds a predetermined threshold value when the outputting of the output item is off in said step of setting the outputting of the output item to on or off.

9. A semiconductor making apparatus, comprising:

a processing chamber for processing a semiconductor wafer;

a power supply for supplying a current, a voltage, or power as an output item necessary for the semiconductor wafer processing;

a control computer for setting a strength of the output item to said power supply and setting the outputting of the output item to on or off;

output sensing means for sensing the output item to provide an output sense signal according to a value obtained by sensing the output item;

means for generating an abnormality

occurrence signal in response to an event in which the output sense signal exceeds a predetermined threshold value when the outputting of the output item is off; and

means connected to said generating means for interrupting the supply of the output item from said power supply to thereby inhibit, according to the abnormality occurrence signal, the processing for a subsequent semiconductor wafer to be processed.

10. A semiconductor making apparatus according to claim 9, further comprising abnormality display means for displaying, in response to the abnormality occurrence signal from said abnormality occurrence signal generating means, an abnormality indication on a screen of an operator's console or an alarm display of said semiconductor making apparatus.

11. A semiconductor wafer fabricating method for use with power supply for supplying power indicating a current or a voltage necessary for processing a semiconductor wafer, comprising the steps of:

setting strength of the power to a predetermined value;

setting the supply of the power to on or off;

sensing present power presently being supply to the semiconductor wafer processing and outputting a sense signal according to a value obtained by sensing the present power;

sensing the power when a power off state is

set in said on or off setting step, determining occurrence of an abnormality when a sense signal according to a value obtained by sensing the power exceeds a predetermined value, and generating an abnormality occurrence signal indicating occurrence of the abnormality; and

inhibiting, in response to the abnormality occurrence signal, the processing for a subsequent semiconductor wafer to be processed.

210822160 022602